## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

T. OTSUBO

Serial No.:

(not yet assigned)

Filed:

August 22, 2003

For:

PLASMA PROCESSING APPARATUS AND PROCESSING

**METHOD** 

## INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97 AND 1.98

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

August 22, 2003

Sir:

In the matter of the above-identified application, this information disclosure statement is being submitted with the following citation as specified in 37 CFR 1.97(d).

"A copy of any patent, publication or other information listed in an information disclosure statement is not required to be provided if it was previously cited by or submitted to the Office in a prior application, provided that the prior application is properly identified in the statement and relied upon for an earlier filing date under 35 U.S.C. 120."

Applicant is submitting herewith a copy of Form PTO-1449 which list documents cited in parent application Serial No. 09/842,000, filed April 26, 2001.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (Case No. 520.39737VX1) and please credit any excess fees to such deposit account.

Respectfully submitted,

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Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DKT. NO. 520.39737VX1	SERIAL NO.	
INFORMAT	ION DISCLOSURE STATEMENT BY APPLICANT	APPLICANT T. OTSUBO		
(Use several sheets if necessary)		FILING DATE August 22, 2003	GROUP	

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